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Sheet 1 of 1

FORM PTO-1449 (REV.7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 97-P-149D1 (850063.518D1)	EXPRESS MAIL NO. EL897859635US
INFORMATION DISCLOSURE STATEMENT <i>(Use several sheets if necessary)</i>		APPLICANT			
		Ming Michael Li		FILING DATE February 6, 2002	GROUP ART UNIT 2825

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
PML	AA	5,182,232	01/26/93	Chhabra et al.	437	200	PTO
PML	AB	5,394,012	02/28/95	Kimura	257	739	10/06/0534
PML	AC	5,418,188	05/23/95	Harper et al.	437	200	06/06/0534
PML	AD	5,585,295	12/17/96	Wu	437	44	10/06/0534
PML	AE	5,599,746	02/04/97	Lur et al.	437	200	
PML	AF	5,767,013	06/16/98	Park et al.	438	622	
PML	AG	5,877,063	03/02/99	Gilchrist	438	398	
PML	AH	5,993,685	11/30/99	Currie et al.	252	79.1	
PML	AJ	6,074,926	06/13/00	Cathey et al.	438	398	
	AJ						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AK					
	AL					
	AM					
	AN					
	AO					

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

PML	AP	Chang, C.Y. and Sze, S.M., "ULSI Technology," 1996, The McGraw-Hill Companies, Inc., pp. 229, 395-397
PML	AQ	Wolf, S., "Silicon Processing for the VLSI Era," Vol. 2 - Process Integration, 1990, Lattice Press, pp. 45, 354-357
	AR	

EXAMINER	Hector N. Roelofs	DATE CONSIDERED	3/30/05
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).			